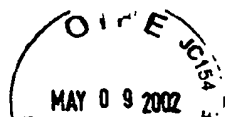


FORM PTO-1449 (Modified)		Attorney Docket No.: 19930-002800US		Application No.: 10/087,040		
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		Applicant: David Miller et al.		Filing Date: February 28, 2002		
		Group: Unassigned		2834		
Reference Designation		U.S. PATENT DOCUMENTS				
		Page 1				
Examiner Initial	Document No.	Date	Name	Class	Sub-class	Filing Date (If Appropriate)
<del>TMV</del> AA	5,414,540	05/09/95	Patel et al.	359	39	
<del>TMV</del> AB	5,917,625	06/29/99	Ogusu et al.	359	130	
<del>TMV</del> AC	5,999,672	12/07/99	Hunter et al.	385	37	
<del>TMV</del> AD	6,028,689	02/22/00	Michalick et al.	359	224	
<del>TMV</del> AE	6,040,935	03/21/00	Michalick	359	198	
<del>TMV</del> AF	6,097,859	08/01/00	Solgaard	385	17	
<del>TMV</del> AG	6,108,471	08/22/00	Zhang et al.	385	37	
<del>TMV</del> AH	6,128,122	10/03/00	Drake et al.	359	224	
<del>TMV</del> AI	09/442,061		Weverka, et al.			11/16/99
	AJ					
	AK					
FOREIGN PATENT DOCUMENTS						
	Document No.	Date	Country	Class	Sub-class	Translation (Yes/No)
	AL					
	AM					
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)						
<del>TMV</del> AN	T. Akiyama, et al.; "Controlled Stepwise Motion in Polysilicon Microstructures," Journal of Microelectromechanical Systems, Vol. 2, No. 3, September 1993; pp.106-110					
<del>TMV</del> AO	Kenneth Bean, et al., "Anisotropic Etching of Silicon," IEEE Transactions on Electron Devices, Vol. Ed-25, No. 10, October 1978					
<del>TMV</del> AP	Dino R. Ciarlo, "A latching accelerometer fabricated by the anisotropic etching of (110) oriented silicon wafers," Lawrence Livermore Nat'l Laboratory, March 1, 1992					
<del>TMV</del> AQ	A.S. Dewa, et al., "Development of a Silicon Two-Axis Micromirror for an Optical Cross-Connect," Solid State Sensors and Actuators Workshop, Hilton Head, South Carolina, pp. 93-96					
<del>TMV</del> AR	Joseph Ford et al., "Wavelength Add Drop Switching Using Tilting Micromirrors," Journal of Lightwave Technology, Vol. 17, No. 5, May 1999					
<del>TMV</del> AS	J. Grade et al., "A Large-Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-8, 2000; pp. 97-100					
<del>TMV</del> AT	V. Kaajakari et al.; "Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction," In MEMS Reliability for Critical Applications, Proceedings of SAPIE Vol. 4180 (2000); pp. 60-65					
<del>TMV</del> AU	T.L. Koch et al., "Anisotropically etched deep gratings for InP/InGaAsP optical devices," J.App. Phys. 62 (8), 15 October 1987					
<del>TMV</del> AV	I. Nishi et al., "Broad-Passband-Width Optical Filter for Multi-Demultiplexer Using a Diffraction Grating and a Retroreflector Prism," Electronics Letters, Vol. 21, No. 10, 9 <sup>th</sup> May 1985					
<del>TMV</del> AW	P. Phillippe et al., "Wavelength demultiplexer: using echelette gratings on silicon substrate," Applied Optics, Vol. 24, No. 7, 1 April 1985					
<del>TMV</del> AX	M. Schilling et al., "Deformation-free overgrowth of reactive ion beam etched submicron structures in InP by liquid phase epitaxy," Appl. Phys. Lett. 49 (12), 22 September 1986					
<del>TMV</del> AY	Z. J. Sun et al., Demultiplexer with 120 channels and 0.29-nm Channel Spacing," IEEE Photonics Technology Letters, Vol. 10, No. 1, January 1998					

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<u>DMO</u> AZ	W. Tang, et al., "Electrostatically Balanced Comb Drive for Controlled Levitation," Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop, June 1990; pp. 198-202		
<u>DMO</u> BA	L. Torcheux et al., "Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions," J. Electrochem.Soc., Vol. 142, No. 6, June 1995		
<u>DMO</u> BB	P. VanKessel et al., "A MEMS-Based Projection Display," Proceedings of the IEEE, Vol. 86, No. 8, August 1998; pp. 1687-1704		
<u>DMO</u> BC	Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion; dissertation by C. Keller, Fall 1998		
<u>DMO</u> BD	Gimballed Electrostatic Microactuators with Embedded Interconnects; dissertation by L. Muller; Spring 2000		
BE			
EXAMINER	<u>Thomas M. Dougherty</u> DATE CONSIDERED <u>December 1, 2003</u>		

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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